

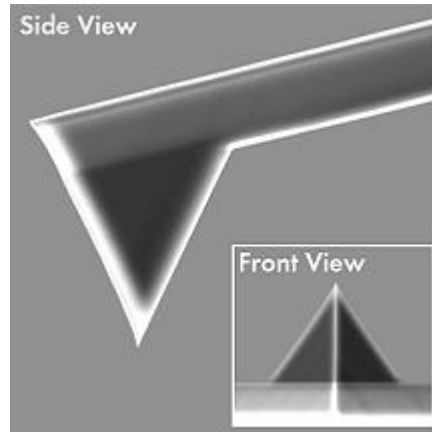
AFM Probe (Silicon, Carbon, Diamond)
STM tip (Platinum-Iridium, Nickel, Tungsten)

Non Contact / Tapping Mode	3 – 8
Force Modulation	8 – 11
Lateral Force	
Electrostatic Force	
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ADT

Diamond AFM Probe	35 - 37
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Non Contact / Tapping Mode AFM Sensors**Arrow UHV Arrow type Silicon AFM Probe**

: 1.5 MHz	
: - N/m	Arrow UHV-10 (Sensor 10)
: 1.0 um	Arrow UHV-20 (Sensor 20)
: 42 um	
: 35 um	

Arrow NC Arrow type Silicon AFM Probe

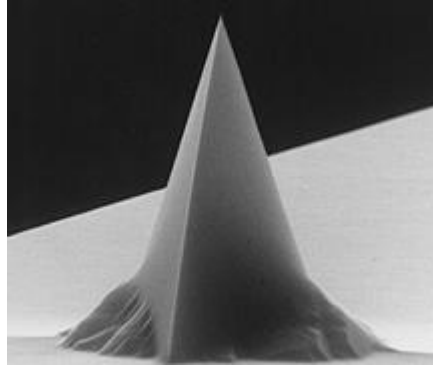
: 285 kHz	
: 42 N/m	Arrow NC-10 (Sensor 10)
: 4.6 um	Arrow NC-20 (Sensor 20)
: 45 um	Arrow NC-50 (Sensor 50)
: 160 um	Arrow NC-W (Sensor 385)

Arrow NCR Arrow type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating	
: 285 kHz	Arrow NCR-10 (Sensor 10)
: 42 N/m	Arrow NCR-20 (Sensor 20)
: 4.6 um	Arrow NCR-50 (Sensor 50)
: 45 um	Arrow NCR-W (Sensor 385)
: 160 um	

Arrow NCPt Arrow type Silicon AFM Probe (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating	
: 285 kHz	Arrow NCPt-10 (Sensor 10)
: 42 N/m	Arrow NCPt-20 (Sensor 20)
: 4.6 um	Arrow NCPt-50 (Sensor 50)
: 45 um	Arrow NCPt-W (Sensor 385)
: 160 um	


NCH Point Probe type Silicon AFM Probe

: 320 kHz	
: 42 N/m	NCH-10 (Sensor 10)
: 4 um	NCH-20 (Sensor 20)
: 30 um	NCH-50 (Sensor 50)
: 125 um	NCH-W (Sensor 385)

NCHR Point Probe type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating	
: 320 kHz	NCHR-10 (Sensor 10)
: 42 N/m	NCHR-20 (Sensor 20)
: 4 um	NCHR-50 (Sensor 50)
: 30 um	NCHR-W (Sensor 385)
: 125 um	

NCHPt Point Probe type Silicon AFM Probe (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating	
: 320 kHz	NCHPt-10 (Sensor 10)
: 42 N/m	NCHPt-20 (Sensor 20)
: 4 um	NCHPt-50 (Sensor 50)
: 30 um	NCHPt-W (Sensor 385)
: 125 um	

NCST Point Probe type Silicon AFM Probe

: 160 kHz	
: 7.4 N/m	NCST-10 (Sensor 10)
: 2.8 um	NCST-20 (Sensor 20)
: 27 um	NCST-50 (Sensor 50)
: 150 um	NCST-W (Sensor 385)

NCSTR Point Probe type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating	
: 160 kHz	NCSTR-10 (Sensor 10)
: 7.4 N/m	NCSTR-20 (Sensor 20)
: 2.8 um	NCSTR-50 (Sensor 50)
: 27 um	NCSTR-W (Sensor 385)
: 150 um	

NCL Point Probe type Silicon AFM Probe, long cantilever

: 190 kHz	NCL-10 (Sensor 10)
: 48 N/m	NCL-20 (Sensor 20)
: 7 um	NCL-50 (Sensor 50)
: 38 um	NCL-W (Sensor 385)
: 225 um	

NCLR Point Probe type Silicon AFM Probe, long cantilever (detector side : Al coating)

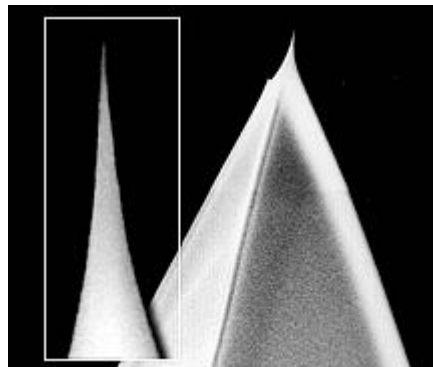
Detector side : Al coating	
: 190 kHz	NCLR-10 (Sensor 10)
: 48 N/m	NCLR-20 (Sensor 20)
: 7 um	NCLR-50 (Sensor 50)
: 38 um	NCLR-W (Sensor 385)
: 225 um	

NCLPt Point Probe type Silicon AFM Probe, long cantilever (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating	
: 190 kHz	NCLPt-10 (Sensor 10)
: 48 N/m	NCLPt-20 (Sensor 20)
: 7 um	NCLPt-50 (Sensor 50)
: 38 um	NCLPt-W (Sensor 385)
: 225 um	

SEIHR Point Probe type Silicon AFM Probe (detector side : Al coating)

Seico Instruments AFM	
Detector side : Al coating	SEIHR-10 (Sensor 10)
: 130 kHz	SEIHR-20 (Sensor 20)
: 15 N/m	SEIHR-50 (Sensor 50)
: 5 um	SEIHR-W (Sensor 385)
: 33 um	
: 225 um	



SSS-NCH Super Sharp type Silicon AFM Probe

: 320 kHz	SSS NCH-10 (Sensor 10)
: 42 N/m	SSS NCH-20 (Sensor 20)
: 4 um	SSS NCH-50 (Sensor 50)
: 30 um	SSS NCH-W (Sensor 385)
: 125 um	

SSS-NCL Super Sharp type Silicon AFM Probe, long cantilever

: 190 kHz
 : 48 N/m
 : 7 μm
 : 38 μm
 : 225 μm

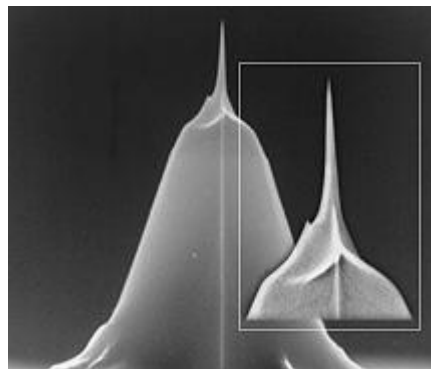
SSS NCL-10 (Sensor 10)
 SSS NCL-20 (Sensor 20)
 SSS NCL-50 (Sensor 50)
 SSS NCL-W (Sensor 385)

SSS-SEIH Super Sharp type Silicon AFM Probe

Seico Instruments AFM

: 130 kHz
 : 15 N/m
 : 5 μm
 : 33 μm
 : 225 μm

SSS SEIHR-10 (Sensor 10)
 SSS SEIHR-20 (Sensor 20)
 SSS SEIHR-50 (Sensor 50)
 SSS SEIHR-W (Sensor 385)



AR5-NCHR High Aspect Ratio type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 320 kHz
 : 42 N/m
 Aspect Ratio >5:1
 : 4 μm
 : 30 μm
 : 125 μm

AR5 NCHR-10 (Sensor 10)
 AR5 NCHR-20 (Sensor 20)
 AR5 NCHR-50 (Sensor 50)
 AR5 NCHR-W (Sensor 385)

AR5T-NCHR Tilt High Aspect Ratio type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 320 kHz
 : 42 N/m
 Aspect Ratio >5:1
 :13
 : 4 μm
 : 30 μm
 : 125 μm

AR5T NCHR-10 (Sensor 10)
 AR5T NCHR-20 (Sensor 20)
 AR5T NCHR-50 (Sensor 50)
 AR5T NCHR-W (Sensor 385)

AR10-NCHR High Aspect Ratio type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

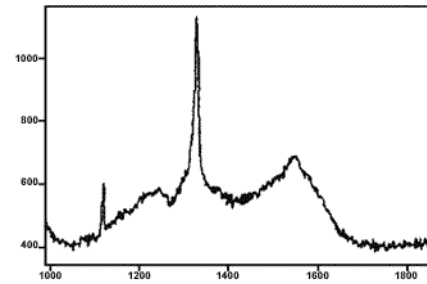
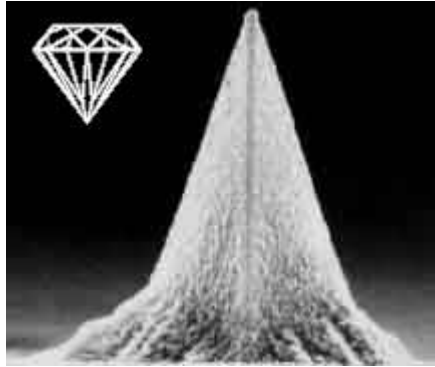
: 320 kHz
 : 42 N/m
 Aspect Ratio >10:1
 : 4 μm
 : 30 μm
 : 125 μm

AR10T NCHR-10 (Sensor 10)
 AR10T NCHR-20 (Sensor 20)
 AR10T NCHR-50 (Sensor 50)
 AR10T NCHR-W (Sensor 385)

AR5-NCLR High Aspect Ratio Silicon AFM Probe, long cantilever (detector side : Al coating)

Detector side : Al coating
 : 190 kHz
 : 48 N/m
 Aspect Ratio >5:1
 : 7 μ m
 : 38 μ m
 : 225 μ m

AR5 NCLR-10 (Sensor 10)
 AR5 NCLR-20 (Sensor 20)
 AR5 NCLR-50 (Sensor 50)
 AR5 NCLR-W (Sensor 385)



Raman spectrum of the diamond coating

DT-NCHR Diamond Coated Silicon AFM Probe (detector : Al coating, tip : diamond coating)

Detector side : Al coating
 Tip side : diamond coating
 : 320 kHz
 : 42 N/m
 : 4 μ m
 : 30 μ m
 : 125 μ m

DT-NCHR-10 (Sensor 10)
 DT-NCHR-20 (Sensor 20)
 DT-NCHR-50 (Sensor 50)
 DT-NCHR-W (Sensor 385)

CDT-NCHR Conductive Diamond Coated (detector : Al coating, tip : conductive diamond)

Detector side : Al coating
 Tip side : conductive diamond coating
 : 320 kHz
 : 42 N/m
 : 4 μ m
 : 30 μ m
 : 125 μ m

CDT-NCHR-10 (Sensor 10)
 CDT-NCHR-20 (Sensor 20)
 CDT-NCHR-50 (Sensor 50)
 CDT-NCHR-W (Sensor 385)

DT-NCLR Diamond Coated, long cantilever (detector : Al coating, tip : diamond coating)

Detector side : Al coating
 Tip side : diamond coating
 : 190 kHz
 : 48 N/m
 : 7 μ m
 : 38 μ m
 : 225 μ m

DT-NCLR-10 (Sensor 10)
 DT-NCLR-20 (Sensor 20)
 DT-NCLR-50 (Sensor 50)
 DT-NCLR-W (Sensor 385)

CDT-NCLR Conductive Diamond Coated, long cantilever (detector : Al, tip : conductive diamond)

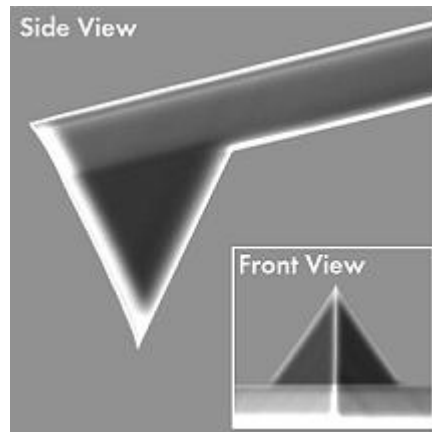
Detector side : Al coating
 Tip side : conductive diamond coating

CDT-NCLR-10 (Sensor 10)

: 190 kHz
 : 48 N/m
 : 7 μm
 : 38 μm
 : 225 μm

CDT-NCLR-20 (Sensor 20)
 CDT-NCLR-50 (Sensor 50)
 CDT-NCLR-W (Sensor 385)

Force Modulation Mode AFM Sensors



Arrow FM Arrow type Silicon AFM Probe

: 75 kHz
 : 2.8 N/m
 : 3.0 μm
 : 35 μm
 : 240 μm

Arrow FM-10 (Sensor 10)
 Arrow FM-20 (Sensor 20)
 Arrow FM-50 (Sensor 50)
 Arrow FM-W (Sensor 385)

Arrow FMR Arrow type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 75 kHz
 : 2.8 N/m
 : 3.0 μm
 : 35 μm
 : 240 μm

Arrow FMR-10 (Sensor 10)
 Arrow FMR-20 (Sensor 20)
 Arrow FMR-50 (Sensor 50)
 Arrow FMR-W (Sensor 385)

Arrow FM Arrow type Silicon AFM Probe

: 75 kHz
 : 2.8 N/m
 : 3.0 μm
 : 35 μm
 : 240 μm

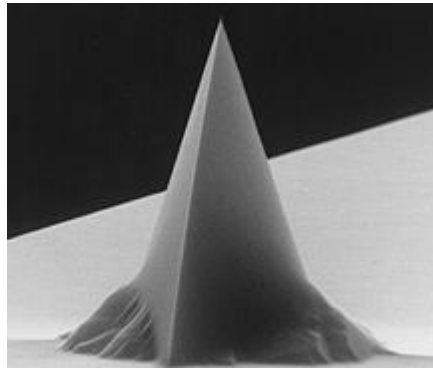
Arrow FM-10 (Sensor 10)
 Arrow FM-20 (Sensor 20)
 Arrow FM-50 (Sensor 50)
 Arrow FM-W (Sensor 385)

Arrow FMR Arrow type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 75 kHz
 : 2.8 N/m
 : 3.0 μm
 : 28 μm
 : 225 μm

Arrow FMR-10 (Sensor 10)
 Arrow FMR-20 (Sensor 20)
 Arrow FMR-50 (Sensor 50)
 Arrow FMR-W (Sensor 385)

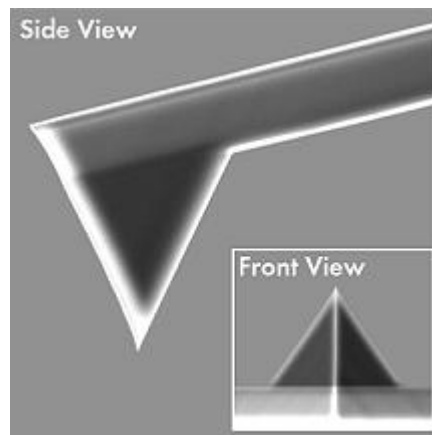


FM Point Probe type Silicon AFM Probe

: 75 kHz	
: 2.8 N/m	FM-10 (Sensor 10)
: 3.0 μ m	FM-20 (Sensor 20)
: 28 μ m	FM-50 (Sensor 50)
: 225 μ m	FM-W (Sensor 385)

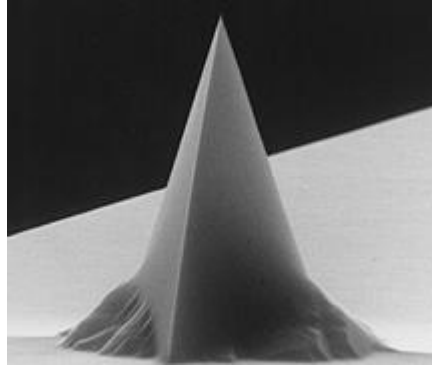
FMR Point Probe type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating	
: 75 kHz	FMR-10 (Sensor 10)
: 2.8 N/m	FMR-20 (Sensor 20)
: 3.0 μ m	FMR-50 (Sensor 50)
: 28 μ m	FMR-W (Sensor 385)
: 225 μ m	



Arrow EFM Electrostatic Force Mode Silicon AFM Probe (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating	
: 75 kHz	Arrow EFM-10 (Sensor 10)
: 2.8 N/m	Arrow EFM-20 (Sensor 20)
: 3.0 μ m	Arrow EFM-50 (Sensor 50)
: 35 μ m	Arrow EFM-W (Sensor 385)
: 240 μ m	



EFM Electrostatic Force Mode Silicon AFM Probe (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating

: 75 kHz	EFM-10 (Sensor 10)
: 2.8 N/m	EFM-20 (Sensor 20)
: 3.0 um	EFM-50 (Sensor 50)
: 28 um	EFM-W (Sensor 385)
: 225 um	

MFMR Magnetic Force Mode Silicon AFM Probe (detector side : Al coating, tip side : Cobalt)

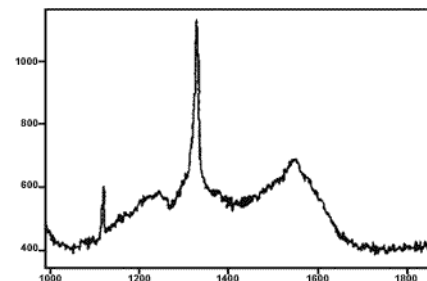
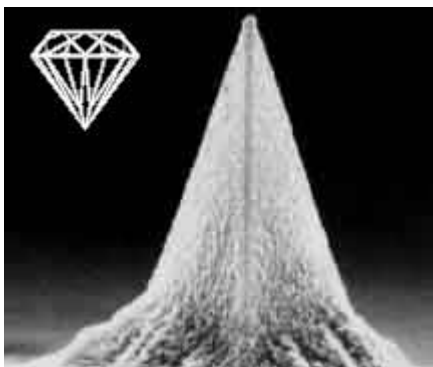
Detector side : Al coating

Tip side : cobalt	MFMR-10 (Sensor 10)
: 75 kHz	MFMR-20 (Sensor 20)
: 2.8 N/m	MFMR-50 (Sensor 50)
: 3.0 um	MFMR-W (Sensor 385)
: 28 um	
: 225 um	

S-MFMR Magnetic Force Mode Silicon AFM Probe (detector side : Al coating, tip side : Cobalt)

Detector side : Al coating

Tip side : cobalt	S-MFMR-10 (Sensor 10)
: 75 kHz	S-MFMR-20 (Sensor 20)
: 2.8 N/m	S-MFMR-50 (Sensor 50)
: 3.0 um	S-MFMR-W (Sensor 385)
: 28 um	
: 225 um	



Raman spectrum of the diamond coating

DT-FMR Diamond Coated Silicon AFM Probe (detector side : Al coating, tip side : diamond)

Detector side : Al coating

Tip side : diamond	DT-FMR-10 (Sensor 10)
: 75 kHz	DT-FMR-20 (Sensor 20)

: 2.8 N/m
 : 3.0 μm
 : 28 μm
 : 225 μm

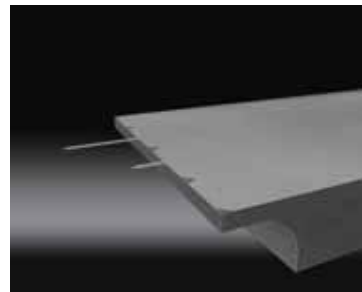
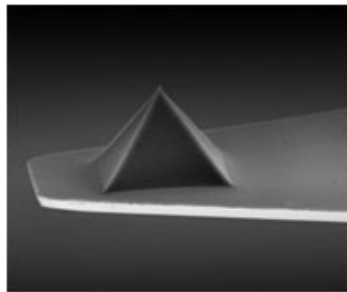
DT-FMR-50 (Sensor 50)
 DT-FMR-W (Sensor 385)

CDT-FMR Conductive Diamond Coated (detector side : Al coating, tip side : conductive diamond)

Detector side : Al coating
 Tip side : conductive diamond
 : 75 kHz
 : 2.8 N/m
 : 3.0 μm
 : 28 μm
 : 225 μm

CDT-FMR-10 (Sensor 10)
 CDT-FMR-20 (Sensor 20)
 CDT-FMR-50 (Sensor 50)
 CDT-FMR-W (Sensor 385)

Contact Mode AFM Sensors

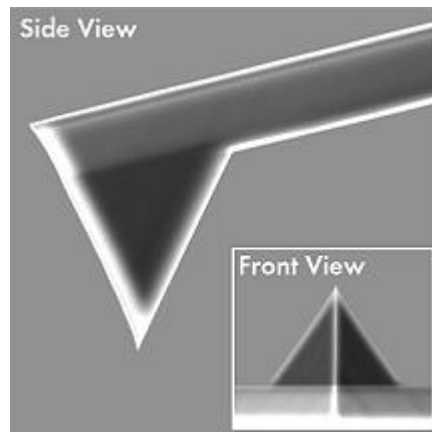


PNP DB Pyrex Nitride Diving Board Cantilever

(Cantilever 1) : 67 kHz
 (Cantilever 2) : 17 kHz
 (Cantilever) : 0.48 N/m
 (Cantilever 2) : 0.06 N/m

PNP-DB-20 (Sensor 20)
 PNP-DB-50 (Sensor 50)

Cantilever 1 : 600 nm, : 40 μm , : 100 μm
 Cantilever 2 : 600 nm, : 40 μm , : 200 μm



Arrow CONT Arrow type Silicon AFM Probe

: 14 kHz
 : 0.2 N/m
 : 2.0 μm
 : 45 μm

Arrow CONT-10 (Sensor 10)
 Arrow CONT-20 (Sensor 20)
 Arrow CONT-50 (Sensor 50)

: 450 um

Arrow CONT-W (Sensor 385)

Arrow CONTR Arrow type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 14 kHz

: 0.2 N/m

: 2.0 um

: 45 um

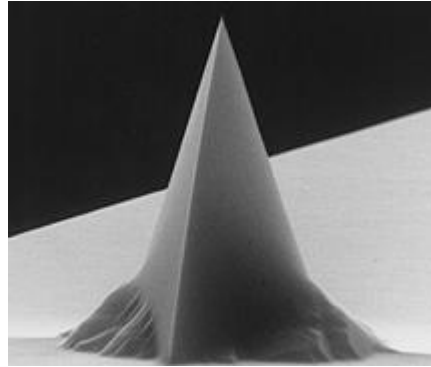
: 450 um

Arrow CONTR-10 (Sensor 10)

Arrow CONTR-20 (Sensor 20)

Arrow CONTR-50 (Sensor 50)

Arrow CONTR-W (Sensor 385)



CONT Point Probe type Silicon AFM Probe

: 13 kHz

: 0.2 N/m

: 2.0 um

: 50 um

: 450 um

CONT-10 (Sensor 10)

CONT-20 (Sensor 20)

CONT-50 (Sensor 50)

CONT-W (Sensor 385)

CONTR Point Probe type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating

: 13 kHz

: 0.2 N/m

: 2.0 um

: 50 um

: 450 um

CONTR-10 (Sensor 10)

CONTR-20 (Sensor 20)

CONTR-50 (Sensor 50)

CONTR-W (Sensor 385)

CONTPt Point Probe type Silicon AFM Probe (detector/tip side : Pt/Ir coating)

Detector/tip side : Pt/Ir coating

: 13 kHz

: 0.2 N/m

: 2.0 um

: 50 um

: 450 um

CONTPt-10 (Sensor 10)

CONTPt-20 (Sensor 20)

CONTPt-50 (Sensor 50)

CONTPt-W (Sensor 385)

CONTSC Point Probe type Silicon AFM Probe

: 23 kHz

: 0.2 N/m

: 1.0 um

: 48 um

: 225 um

CONTSC-10 (Sensor 10)

CONTSC-20 (Sensor 20)

CONTSC-50 (Sensor 50)

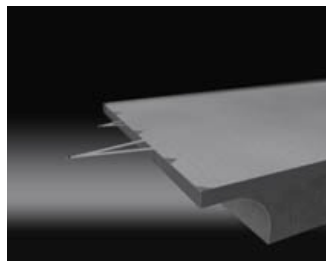
CONTSC-W (Sensor 385)

CONTSCR Point Probe type Silicon AFM Probe (detector side : Al coating)

Detector side : Al coating	
: 23 kHz	CONTSCR-10 (Sensor 10)
: 0.2 N/m	CONTSCR-20 (Sensor 20)
: 1.0 μ m	CONTSCR-50 (Sensor 50)
: 48 μ m	CONTSCR-W (Sensor 385)
: 225 μ m	

ZEILR Point Probe type Silicon AFM Probe (detector side : Al coating)

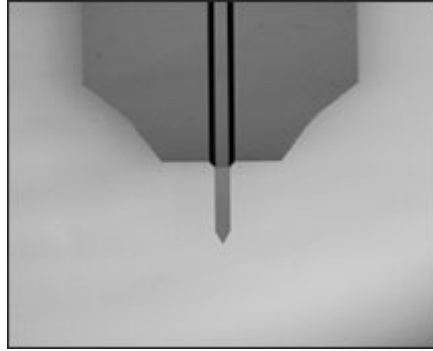
Zeiss Veritekt AFM	
Detector side : Al coating	ZEILR-10 (Sensor 10)
: 27 kHz	ZEILR-20 (Sensor 20)
: 1.6 N/m	ZEILR-50 (Sensor 50)
Low Force Constant	ZEILR-W (Sensor 385)
: 5 μ m	
: 57 μ m	
: 225 μ m	

Tipless Cantilever**PNP-TR-TL Tipless Pyrex Nitride Diving Board Cantilever**

(Cantilever 1) : 67 kHz	
(Cantilever 2) : 17 kHz	PNP-TR-TL-20 (Sensor 20)
(Cantilever) : 0.48 N/m	PNP-TR-TL-50 (Sensor 50)
(Cantilever 2) : 0.06 N/m	
Cantilever shape : triangular	
Cantilever 1 : 600 nm, : 40 μ m, : 100 μ m	
Cantilever 2 : 600 nm, : 40 μ m, : 200 μ m	

PNP-TR-TL-Au Tipless Pyrex Nitride Diving Board Cantilever

Top side : 5nm Titanium, 30nm Gold coating	
(Cantilever 1) : 67 kHz	PNP-TR-TL-Au-20 (Sensor 20)
(Cantilever 2) : 17 kHz	PNP-TR-TL-Au-50 (Sensor 50)
(Cantilever) : 0.48 N/m	
(Cantilever 2) : 0.06 N/m	
Cantilever shape : triangular	
Cantilever 1 : 600 nm, : 40 μ m, : 100 μ m	
Cantilever 2 : 600 nm, : 40 μ m, : 200 μ m	


Arrow TL1 Tipless Arrow type Silicon AFM Probe

: 6 kHz
 : 0.03 N/m
 : 1.0 μm
 : 100 μm
 : 500 μm
 Cantilever 1

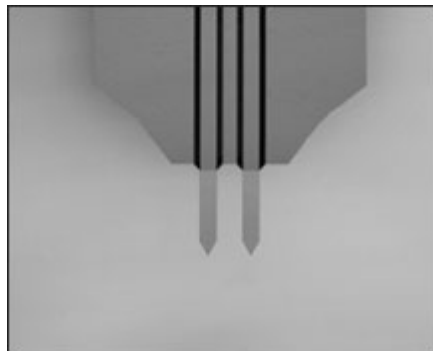
Arrow TL1-50 (Sensor 50)

Arrow TL1Au Tipless Arrow type Silicon AFM Probe (top side : 5nm Titanium, 30nm Gold coating)

Top side : 5nm Titanium, 30nm Gold coating

: 6 kHz
 : 0.03 N/m
 : 1.0 μm
 : 100 μm
 : 500 μm
 Cantilever 1

Arrow TL1Au-50 (Sensor 50)


Arrow TL2 Tipless Arrow type Silicon AFM Probe

: 6 kHz
 : 0.03 N/m
 : 1.0 μm
 : 100 μm
 : 500 μm
 Cantilever 2
 Cantilever Pitch : 250 μm

Arrow TL2-50 (Sensor 50)

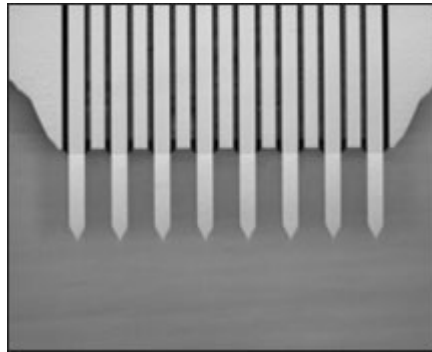
Arrow TL2Au Tipless Arrow type Silicon AFM Probe (top side : 5nm Titanium, 30nm Gold coating)

Top side : 5nm Titanium, 30nm Gold coating

: 6 kHz
 : 0.03 N/m
 : 1.0 μm

Arrow TL2Au-50 (Sensor 50)

: 100 um
 : 500 um
 Cantilever 2
 Cantilever Pitch : 250 um



Arrow TL8 Tipless Arrow type Silicon AFM Probe

: 6 kHz
 : 0.03 N/m
 : 1.0 um
 : 100 um
 : 500 um
 Cantilever 8
 Cantilever Pitch : 250 um

Arrow TL8-50 (Sensor 50)

Arrow TL8Au Tipless Arrow type Silicon AFM Probe (top side : 5nm Titanium, 30nm Gold coating)

Top side : 5nm Titanium, 30nm Gold coating
 : 6 kHz
 : 0.03 N/m
 : 1.0 um
 : 100 um
 : 500 um
 Cantilever 8
 Cantilever Pitch : 250 um

Arrow TL8Au-50 (Sensor 50)

STM tip SPM

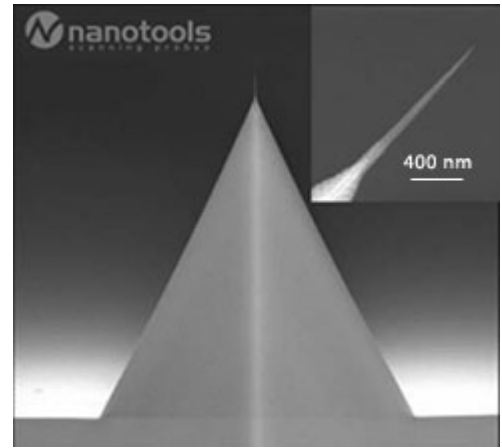
STM tip	Pt/Ir			
	0.25 mm	30 cm	Wire	
	Wire Cutter			
	10m, 20m 30m		가	
Alignment Chip				
ALIGN-10	Pointprobe, Diamond Coated, High Aspect Ratio, Super Sharp			
	Alignment Chip Set. 10			
Tip Storage Kit				
TS-KIT	10	ESD Safe Gel Pak		
ESD Safe Handling Kit				
ESD-KIT		, 3 m	,	,
Calibration Standards				
2D100	SPM	XY	Lateral Calibration Standard	
			, 100 nm pitch	
2D200	SPM	XY	Lateral Calibration Standard	
			, 200 nm pitch	
2D300	SPM	XY	Lateral Calibration Standard	
			, 300 nm pitch	
H8		Z	Height Standard	
	8 nm			
FLAT	Flatness Standard			

가

<p>높은 중횡비 탄소나노탐침 높은 중횡비 측정에 필요한 탁월한 내구성과 신뢰성을 가진 탐침</p>	<p>M1_ArrowNC_13 M1_NCH_13 M1_ESD_NCH_13 MC90-70_ArrowNCR_3 MC60_ArrowNCR_3 MSS_NCHR_13 MSS_NCHR_3 MSS_FMR_13 MSS_FMR_3 CNT300_ArrowNCR_3 EBD2-100_NCH_13 EBD2-100_NCH_3 EBD2-100_NCHR_3</p>
<p>고분해능 탄소나노탐침 매우 예리한 모양의 특수한 Tapping Mode AFM 측정을 위한 탐침</p>	<p>SSE_NCHR_13</p>
<p>범용 탄소나노탐침 고속 원자현미경 측정, 생물학과 나노결각 적용에 적합한 탐침</p>	<p>biotool_PNP_TR_10 B1, B2, B50, B100, B150</p>

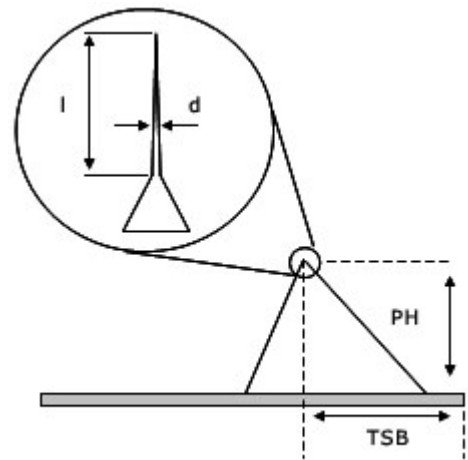
M1_ArrowNC_13

The nanotools® M1_ArrowNC_13 tip is designed for non-contact / high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Excellent lifetime and reliability for high aspect ratio applications are key features.



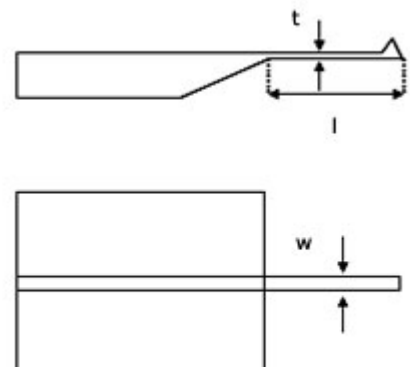
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	800 nm	+/- 200 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 600nm	70 nm	+/- 10 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10–15 um
Tip set back (TSB)	5.2 um	4- 5.5 um



Cantilever Spec

	nominal	range
Type	Arrow NC	
Shape	beam	
Force constant	42 N/m	27–80 N/m
Resonance frequency	285 kHz	240-380 kHz
length (l)	160 nm	150-170 nm
Width (w)	45 um	32.5–52.5 um
Thickness (t)	4 um	3–5 um

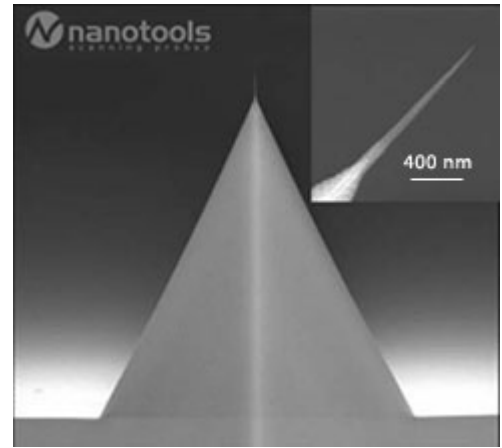


Coating

Tip side : none
 Back side : none

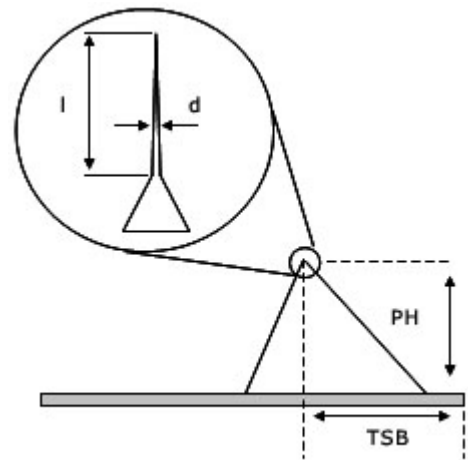
M1_NCH_13

The nanotools® M1_NCH_13 tip is designed for non-contact / high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Excellent lifetime and reliability for high aspect ratio applications are key features.



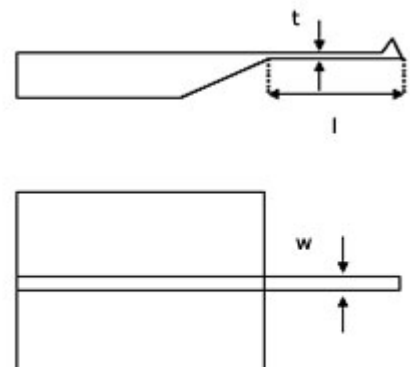
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	800 nm	+/- 200 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 600nm	70 nm	+/- 10 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10–15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27–75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22–38 um
Thickness (t)	4 um	3–5 um

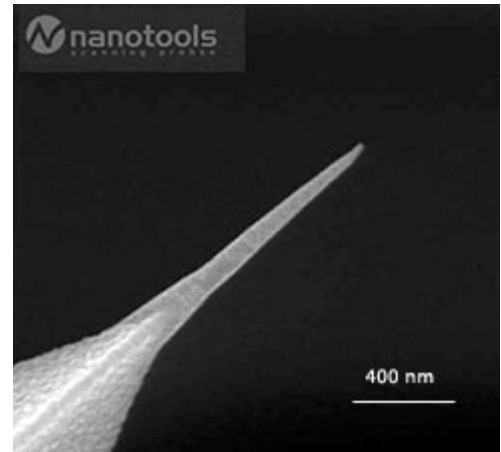


Coating

Tip side : none
Back side : none

M1_ESD_NCH_13

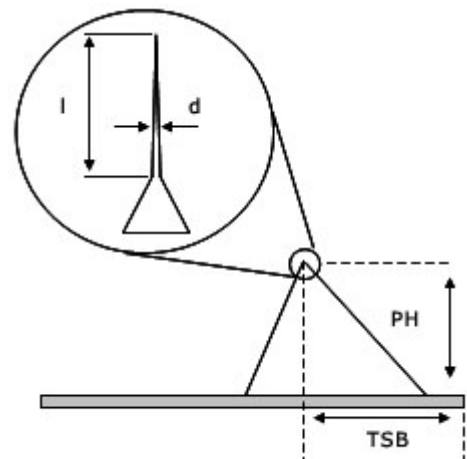
The nanotools® M1-ESD_NCH_13 probes are designed for non-contact/ high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Its special anti-ESD coating delivers metallic conductivity of the probe without weakening its mechanical strength. For most applications the conductivity of the standard probe (either EBD or highly doped silicon) is sufficient to dissipate static charge - an electric discharge would immediately destroy the tip. However, some applications such as scanning ceramics or photomasks require an even higher level of ESD precautions. Therefore the nanotools® M1-ESD_NCH_13 is the choice.



Key features are excellent lifetime and reliability for high aspect ratio applications, where charging of the sample is an issue.

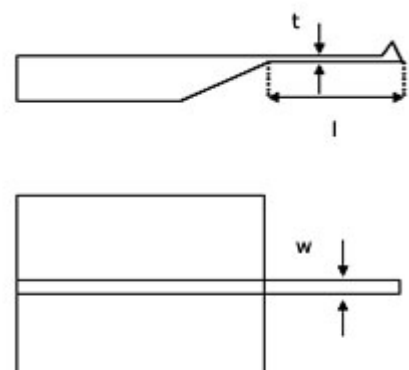
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	800 nm	+/- 200 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 600nm	70 nm	+/- 10 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	Range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



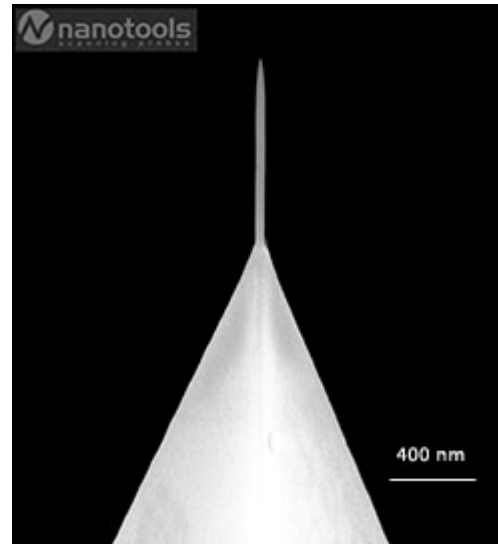
Coating

Tip side : very thin Al

Back side : none

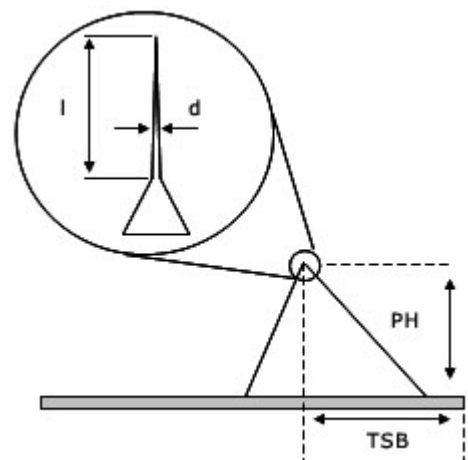
MC90-70_ArrowNCR_3

The nanotools® MC90/70 probes feature a perfectly cylindrical tip shape providing the highest repeatability of depth and bottom width measurements (constant bottom travel distance). The nanotools® MC90/70 high aspect ratio probes with cylindrical shape are the AFM In-Line metrology solution for 90 nm and 70 nm. MC tips are tilt compensated and are available for most AFM systems.



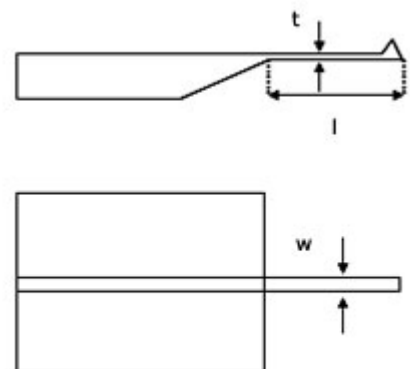
Tip Spec

	nominal	range
Shape	cylindrical	
Tip length (l)	800 nm	+/- 200 nm
Tip radius (r)	< 5 nm	+/- 7 nm
Tip diameter (d)	55 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10–15 um
Tip set back (TSB)	5.2 um	4- 5.5 um



Cantilever Spec

	nominal	Range
Type	ArrowNCR	
Shape	beam	
Force constant	42 N/m	27–80 N/m
Resonance frequency	285 kHz	240-380 kHz
length (l)	160 nm	150-170 nm
Width (w)	45 um	37.5–52.5 um
Thickness (t)	4 um	3–5 um



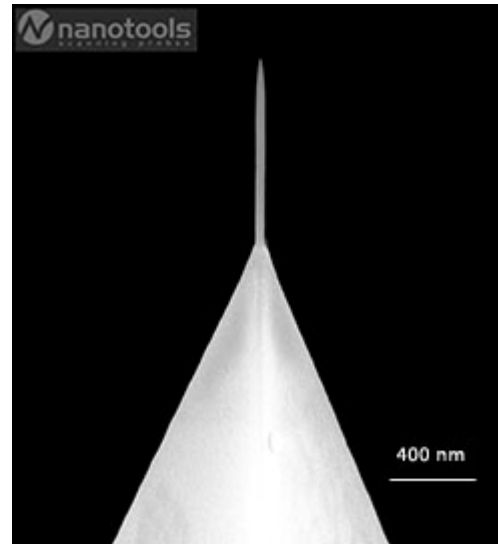
Coating

Tip side : none

Back side : 30 nm Al reflex

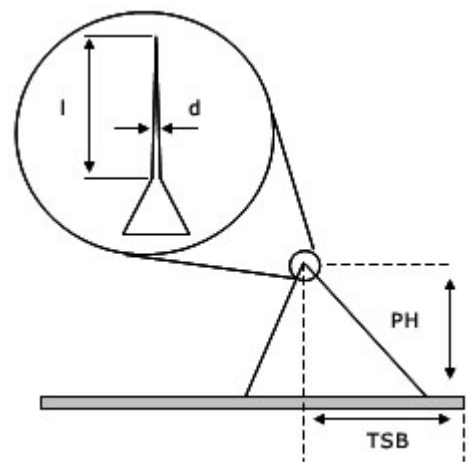
MC60_ArrowNCR_3

The nanotools® MC60 probes feature a perfectly cylindrical tip shape providing the highest repeatability of depth and bottom width measurements (constant bottom travel distance). The nanotools® MC60 high aspect ratio probes with cylindrical shape are the AFM In-Line metrology solution for 60 nm. MC tips are tilt compensated and are available for most AFM systems.



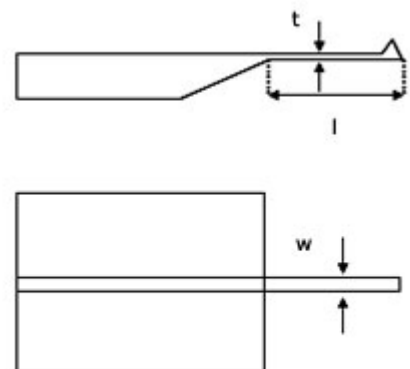
Tip Spec

	nominal	range
Shape	cylindrical	
Tip length (l)	500 nm	+/- 100 nm
Tip radius (r)	< 5 nm	+/- 7 nm
Tip diameter (d)	30 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10–15 um
Tip set back (TSB)	5.2 um	4- 5.5 um



Cantilever Spec

	nominal	Range
Type	ArrowNCR	
Shape	beam	
Force constant	42 N/m	27–80 N/m
Resonance frequency	285 kHz	240-380 kHz
length (l)	160 nm	150-170 nm
Width (w)	45 um	37.5–52.5 um
Thickness (t)	4 um	3–5 um



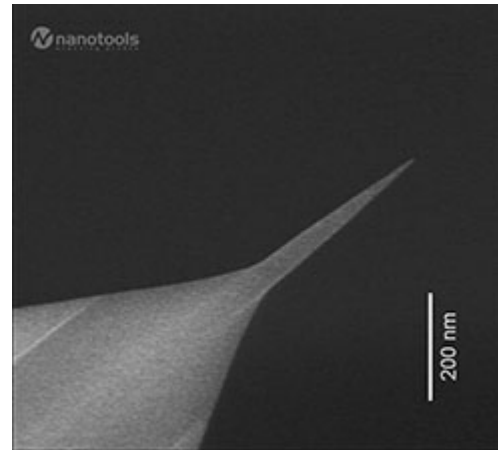
Coating

Tip side : none

Back side : 30 nm Al reflex

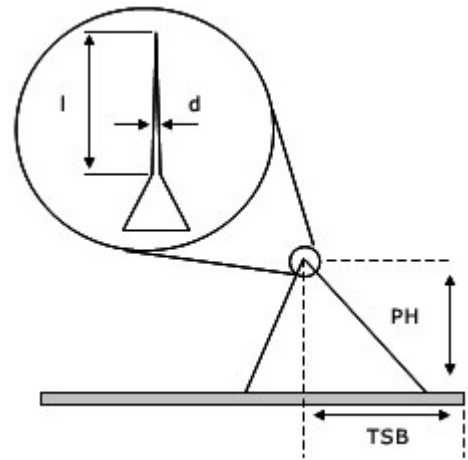
MSS_NCHR_13

Multipurpose high resolution probe with excellent lifetime and reliability. The nanotools® MSS_NCHR_13 tip is designed for non-contact / high frequency mode. It delivers outstanding resolution in critical AFM applications even on hard, tip eating samples like ceramics, silicon oxide/nitride or polysilicon to name a few.



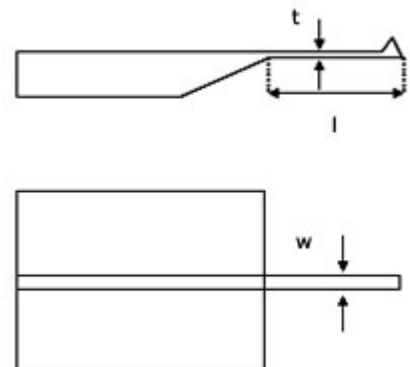
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	400 nm	+/- 100 nm
Tip radius (r)	< 2-3 nm	+/- 5 nm
Tip diameter (d) measured at 300nm	20 nm	+/- 5 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



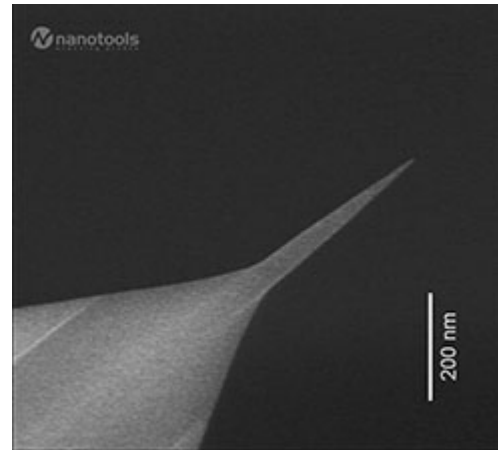
Coating

Tip side : none

Back side : 30 nm Al reflex

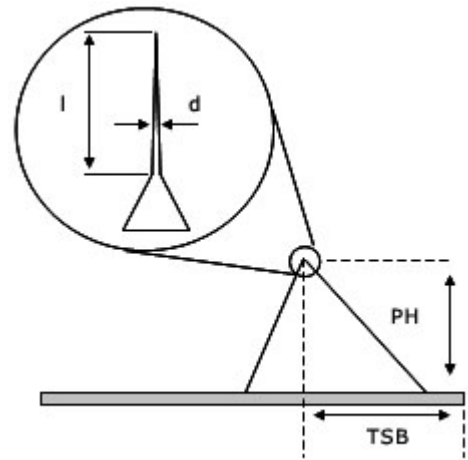
MSS_NCHR_3

Multipurpose high resolution probe with excellent lifetime and reliability. The nanotools® MSS_NCHR_3 tip is designed for non-contact / high frequency mode. It delivers outstanding resolution in critical AFM applications even on hard, tip eating samples like ceramics, silicon oxide/nitride or polysilicon to name a few.



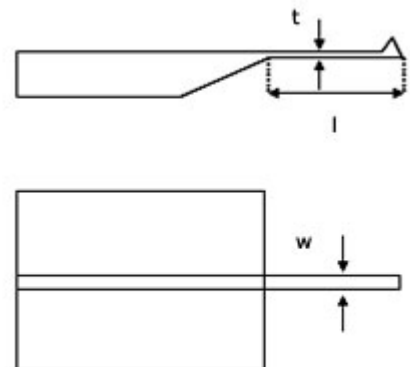
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	400 nm	+/- 100 nm
Tip radius (r)	< 2-3 nm	+/- 5 nm
Tip diameter (d) measured at 300nm	20 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 1 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



Coating

Tip side : none

Back side : 30 nm Al reflex

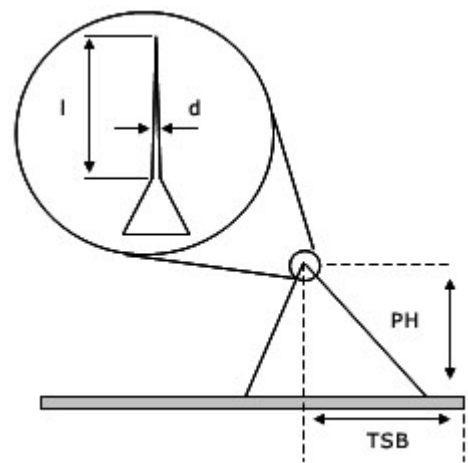
MSS_FMR_13

Due to the softer FMR cantilever this multipurpose high resolution probe approaches ultimate lifetime and reliability. The special qualities of our MSS PatternedMedia also lead to the best interaction between tip and cantilever. The nanotools® MSS_FMR_13 tip is designed for non-contact / high frequency mode. It delivers outstanding resolution in critical AFM applications even on hard, tip eating samples like ceramics, silicon oxide/nitride or polysilicon to name a few.



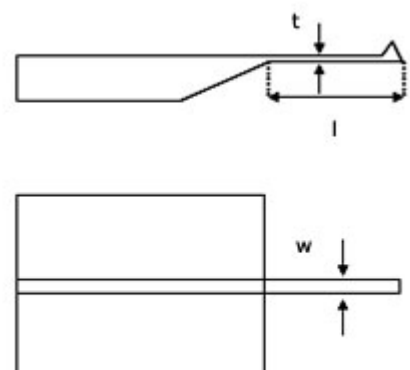
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	400 nm	+/- 100 nm
Tip radius (r)	< 2-3 nm	+/- 5 nm
Tip diameter (d) measured at 300nm	15 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 1 deg
Pyramid height (PH)	15 um	10–15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	FMR	
Shape	beam	
Force constant	2.8 N/m	0.5–9.5 N/m
Resonance frequency	75 kHz	40-115 kHz
length (l)	225 nm	215-235 nm
Width (w)	28 um	20–35 um
Thickness (t)	3 um	2–4 um

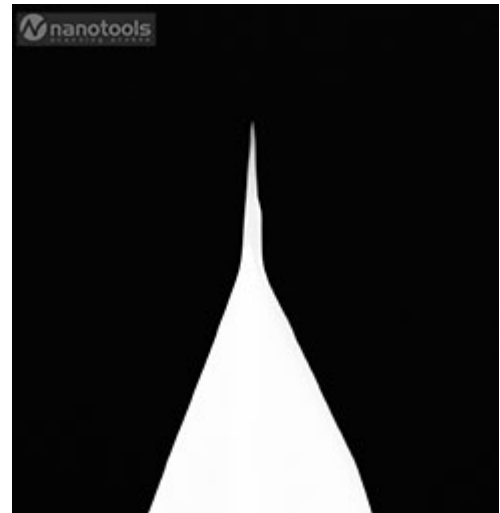


Coating

Tip side : none
 Back side : reflex

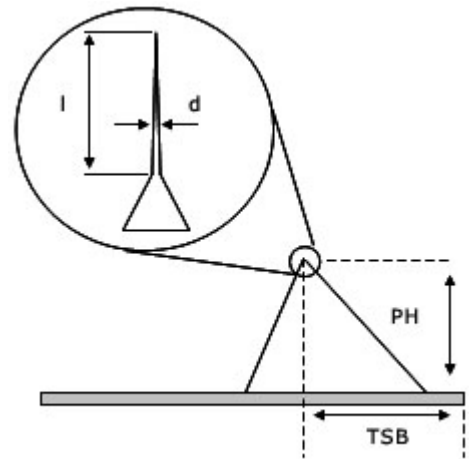
MSS_FMR_3

Due to the softer FMR cantilever this multipurpose high resolution probe approaches ultimate lifetime and reliability. The special qualities of our MSS PatternedMedia also lead to the best interaction between tip and cantilever. The nanotools® MSS_FMR_3 tip is designed for non-contact / high frequency mode. It delivers outstanding resolution in critical AFM applications even on hard, tip eating samples like ceramics, silicon oxide/nitride or polysilicon to name a few.



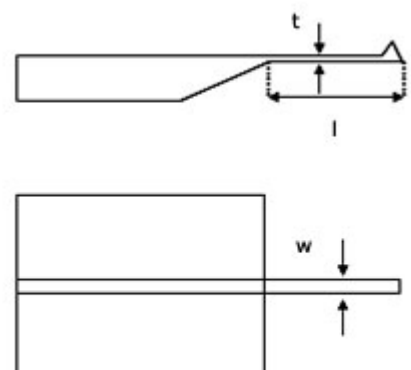
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	400 nm	+/- 100 nm
Tip radius (r)	< 2-3 nm	+/- 5 nm
Tip diameter (d) measured at 300nm	15 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	FMR	
Shape	beam	
Force constant	2.8 N/m	0.5-9.5 N/m
Resonance frequency	75 kHz	40-115 kHz
length (l)	225 nm	215-235 nm
Width (w)	28 um	20-35 um
Thickness (t)	3 um	2-4 um



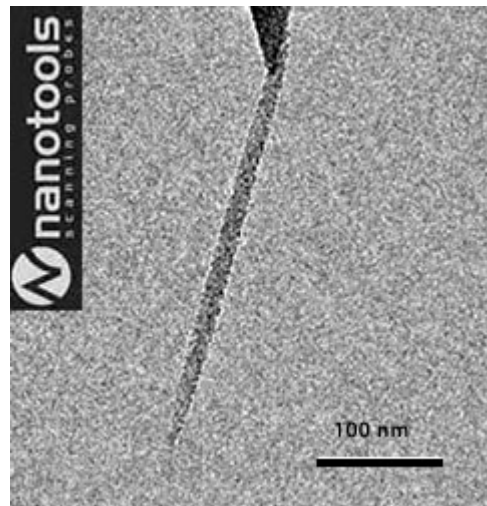
Coating

Tip side : none
 Back side : reflex

CNT300_ArrowNCR_3

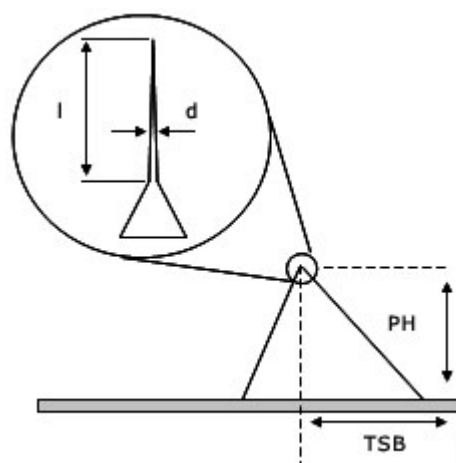
The nanotools® M*-CNT is not using a multiwall carbon nanotube attached to a silicon cantilever. Moreover we pushed our proven EBD technology to the dimensions of a CNT, but maintaining EBD's key strength: precise tip orientation, precise control in tip dimensions (length and diameter), large volume production. What is critical in nanotube technology is solved for the M*-CNT:

- controlled tip length
- controlled tip orientation (angle accuracy better 0.5deg)
- automated fabrication process



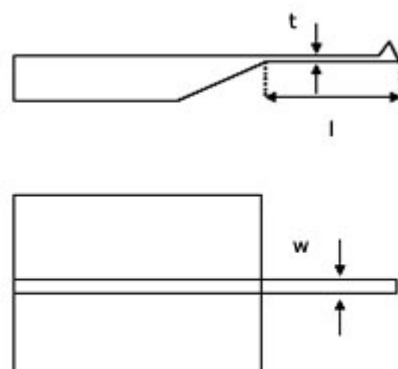
Tip Spec

	nominal	range
Shape	cylindrical	
Tip length (l)	300 nm	+/- 50 nm
Tip radius (r)	< 2-3 nm	+/- 5 nm
Tip diameter (d)	20 nm	+/- 5 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	5.2 um	4- 5.5 um



Cantilever Spec

	nominal	Range
Type	ArrowNCR	
Shape	beam	
Force constant	42 N/m	27-80 N/m
Resonance frequency	285 kHz	240-380 kHz
length (l)	160 nm	150-170 nm
Width (w)	45 um	37.5-52.5 um
Thickness (t)	4.6 um	3.6-5.6 um



Coating

Tip side : none
 Back side : 30 nm Al reflex

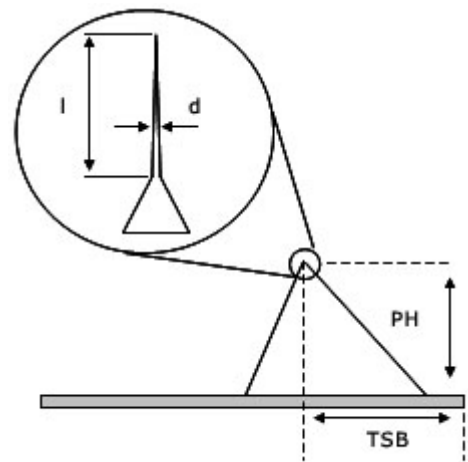
EBD2-100_NCH_13

The nanotools® EBD2-100_NCH_13 tip is designed for non-contact / high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Excellent lifetime and reliability for high aspect ratio applications are key features.



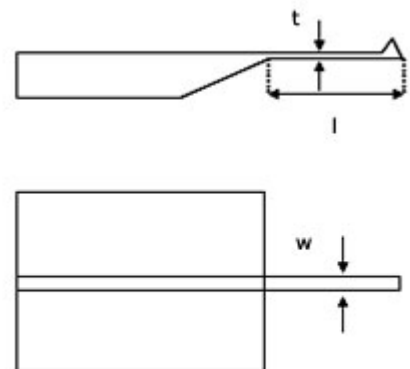
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	2000 nm	+/- 600 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 1000nm	< 100 nm	80-100 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



Coating

Tip side : none
Back side : none

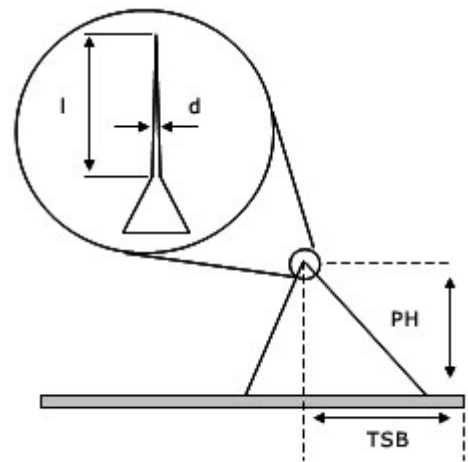
EBD2-100_NCH_3

The nanotools® EBD2-100_NCH_3 tip is designed for non-contact / high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Excellent lifetime and reliability for high aspect ratio applications are key features.



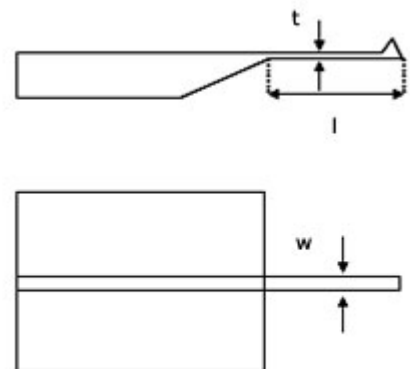
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	2000 nm	+/- 600 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 1000nm	< 100 nm	80-100 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



Coating

Tip side : none
Back side : none

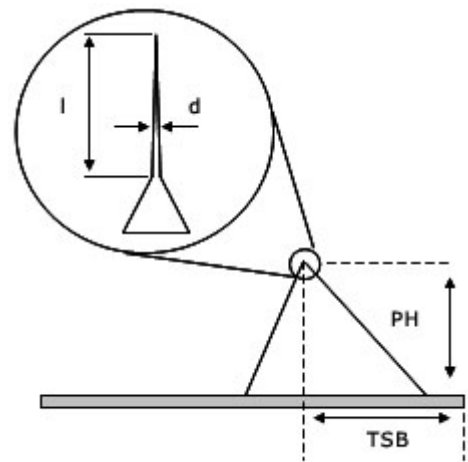
EBD2-100_NCHR_3

The nanotools® EBD2-100_NCHR_3 tip is designed for non-contact / high frequency mode, in particular for automated AFM systems for in-line process control as well as general purpose AFM. Excellent lifetime and reliability for high aspect ratio applications are key features.



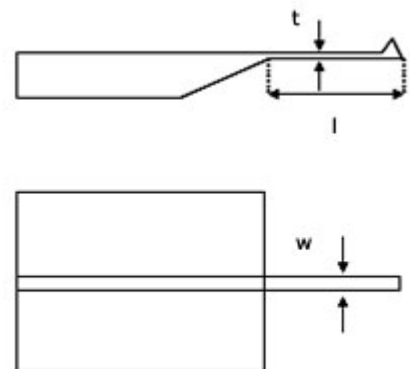
Tip Spec

	nominal	range
Shape	conical	
Tip length (l)	2000 nm	+/- 600 nm
Tip radius (r)	< 5 nm	+/- 10 nm
Tip diameter (d) measured at 1000nm	< 100 nm	80-100 nm
Tilt compensation	3 deg	+/- 0.5 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resonance frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



Coating

Tip side : none

Back side : 30 nm Al reflex

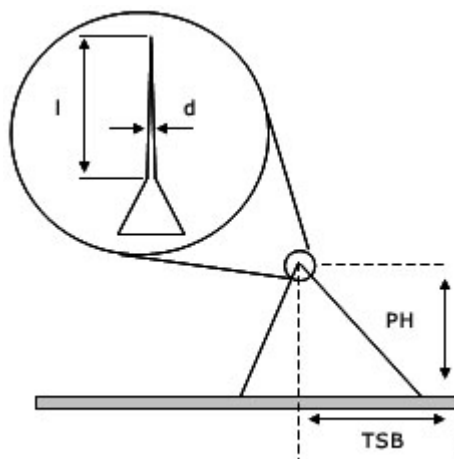
SSE_NCHR_13

2 nm tip radius, high resolution probe with excellent lifetime and reliability. The nanotools® SSE - SuperSharp Enhanced is designed for non-contact / high frequency mode. It delivers outstanding resolution and image stability in critical AFM applications even on hard, tip eating samples like ceramics, silicon oxide/nitride, polysilicon to name a few.



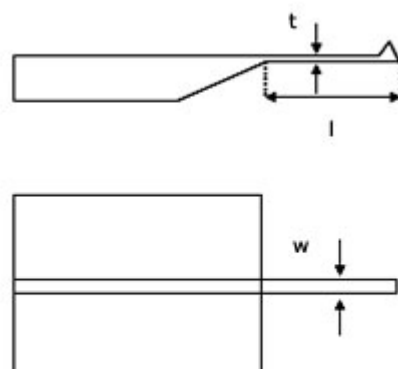
Tip Spec

	nominal	range
Shape	conical	
Tip radius (r)	2-3 nm	< 5 nm
Tilt compensation	13 deg	+/- 1 deg
Pyramid height (PH)	15 um	10-15 um
Tip set back (TSB)	15 um	5- 25 um



Cantilever Spec

	nominal	range
Type	TESP/NCH	
Shape	beam	
Force constant	42 N/m	27-75 N/m
Resolution frequency	320 kHz	270-350 kHz
length (l)	125 nm	115-135 nm
Width (w)	30 um	22-38 um
Thickness (t)	4 um	3-5 um



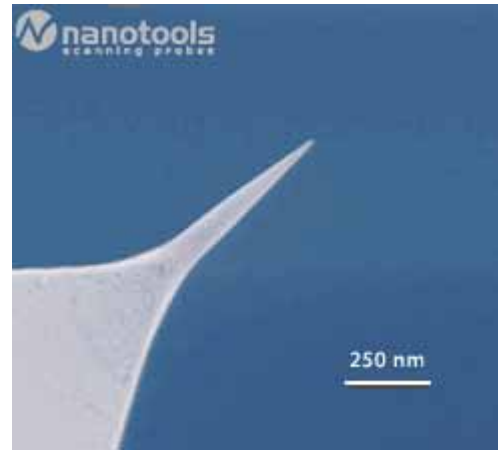
Coating

Tip side : none

Back side : 30 nm Al reflex

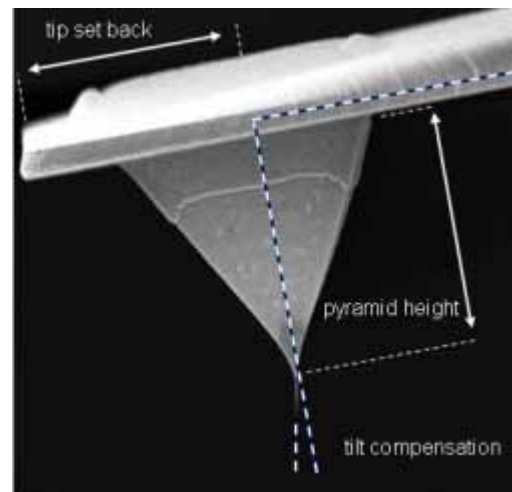
biotool_PNP_TR_10

The nanotools **EBD probe biotool** is specifically designed for biological applications. It is extremely **appropriate for small features** and compatible with both air and liquids. With this probe you get **true dimensions of fine structures** and **clear sidewall information**.



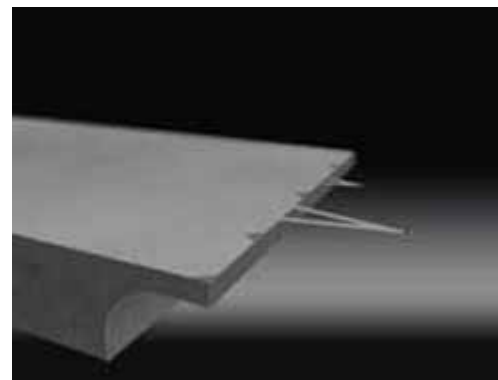
Tip Spec

	nominal	range
Shape	conical	
Tip length (r)	550 nm	+/- 250 nm
Tip radius (r)	< 5 nm	< 10 nm
Tilt compensation	10 deg	+/- 1 deg
Pyramid height (PH)	4 um	
Tip set back (TSB)	4 um	



Cantilever Spec

	nominal
Type	PNP_TR
Shape	triangle
Force constant	0.32 N/m
Resolution frequency	67 kHz
length (l)	100 nm
Width (w)	135 um
Thickness (t)	0.6 um

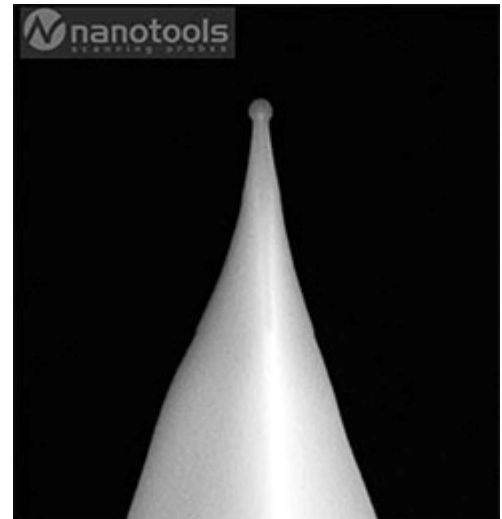


Coating

Tip side : none
 Back side : 65 nm Au reflex

B1, B2, B50, B100, B150

This SPM probe offers a hemispherical, symmetric and extremely smooth hard tip side coating. This coating, made of EBD diamond like carbon, features extremely high wear resistance. The macroscopic tip radius of curvature is precise to +/- 5 nm of the nominal value.



	B1 (r: 10-25 nm)	B2 (r: 30-50 nm)	B50 (r: 50 nm +/- 10%)	B100 (r: 100 nm +/- 10%)	B150 (r: 150 nm +/- 10%)
NCHR l: 125 μm w: 30 μm t: 4 μm k: 42 N/m f: 320 kHz	B1_NCHR	B2_NCHR	B50_NCHR	B100_NCHR	B150_NCHR
FMR l: 225 μm w: 28 μm t: 3 μm k: 2.8 N/m f: 75 kHz	B1_FMR	B2_FMR	B50_FMR	B100_FMR	B150_FMR
CONTR l: 450 μm w: 50 μm t: 2 μm k: 0.2 N/m f: 13 kHz	B1_CONTR	B2_CONTR	B50_CONTR	B100_CONTR	B150_CONTR

Coating / Tip Shape

Tip shape : hemispherical

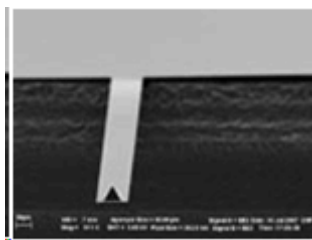
Tip side : none

Back side : 30 nm Al reflex

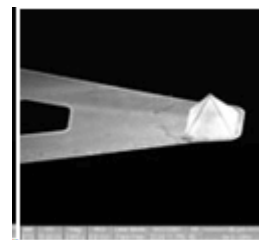
Diamond AFM Probes

- Si SiN AFM Probe 100 가
- Si SiN AFM Probe 가
- 20nm 30nm 20nm
-
-

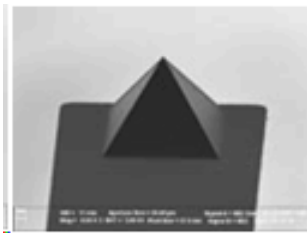
NaDia All Diamond AFM Probe



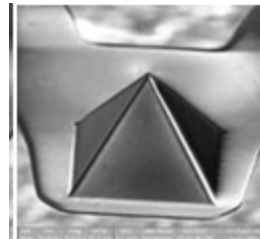
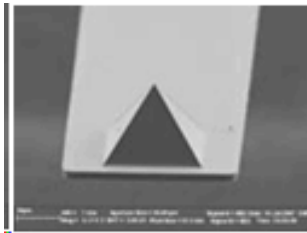
Rectangular Cantilever



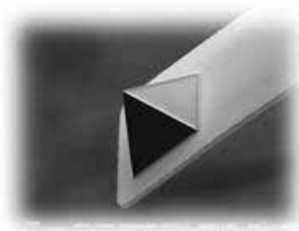
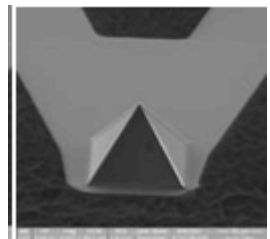
Triangular Cantilever



Rectangular tip





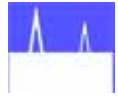

Triangular tip



NaDia All Diamond AFM Probe

ND-CTC Series : Conductive All Diamond Probe

Tip		Cantilever	
Shape	(111) Pyramid	Tip Setback	9 μ m
Height	5.66 μ m	Coating	60 nm reflective aluminum coating
Radius	15 - 30 nm (nominal)	Curvature	Typically less than 3 degrees
Material	Conductive UNCD	Curvature	Standard size Pyrex (3.6 x 1.5 x 0.5 mm)

Model	Chip Image	Cantilever	Force Constant (N/m)	Frequency (kHz)	Length (μ m)	Width (μ m)	Thickness (μ m)
ND-CTCR1-2		Short Medium Long	0.35 0.17 0.04	35 17 12	225 325 425	30 40 20	1 1 1
ND-CTCR2-2		Short Medium Long	0.23 0.08 0.05	40 12 8	225 425 500	20 40 40	1 1 1
ND-CTCT1-2		Short Long	1.28 0.46	48 24	200 300	25 41	1 1
ND-CTCT2-2		Short Long	0.71 0.04	50 23	200 300	17 23	1 1




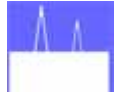
ND-DYI Series : Dynamic Mode All Diamond Probe

Tip		Cantilever	
Shape	(111) Pyramid	Tip Setback	9 μ m
Height	5.66 μ m	Coating	60 nm reflective aluminum coating
Radius	15 - 30 nm (nominal)	Curvature	Typically less than 3 degrees
Material	UNCD	Curvature	Standard size Pyrex (3.6 x 1.5 x 0.5 mm)

Model	Cantilever	Force Constant (N/m)	Frequency (kHz)	Length (μ m)	Width (μ m)	Thickness (μ m)
ND-DYIRS-4	1 Cantilever per chip	34	310	120	33	2.5
ND-DYIRL-4	1 Cantilever per chip	28	240	130	33	2.5

ND-CTI Series : Contact Mode All Diamond Probe

Tip		Cantilever	
Shape	(111) Pyramid	Tip Setback	9 um
Height	5.66 um	Coating	60 nm reflective aluminum coating
Radius	15 - 30 nm (nominal)	Curvature	Typically less than 3 degrees
Material	Conductive UNCD	Curvature	Standard size Pyrex (3.6 x 1.5 x 0.5 mm)

Model	Chip Image	Cantilever	Force Constant (N/m)	Frequency (kHz)	Length (um)	Width (um)	Thickness (um)
ND-CTIR1-4		Short Medium Long	0.35 0.17 0.04	35 17 12	225 325 425	30 40 20	1 1 1
ND-CTIR2-4		Short Medium Long	0.23 0.08 0.05	40 12 8	225 425 500	20 40 40	1 1 1
ND-CTIT1-4		Short Long	1.28 0.46	48 24	200 300	25 41	1 1
ND-CTIT2-4		Short Long	0.71 0.04	50 23	200 300	17 23	1 1